

SPUTTERING TARGET MATERIAL FOR PRODUCING
INTERMEDIATE LAYER FILM OF PERPENDICULAR MAGNETIC
RECORDING MEDIUM AND THIN FILM PRODUCED BY USING
THE SAME

ABSTRACT

There is disclosed a sputtering target material for
producing an intermediate layer film of a perpendicular
5 magnetic recording medium, which is capable of dramatically
reducing the crystal grain size of a thin film formed by
sputtering. The sputtering target material comprises, in at %,
1 to 20% of W; 0.1 to 10% in total of one or more elements
selected from the group consisting of P, Zr, Si and B; and
10 balance Ni.